



1Fw 2125

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shigeyuki UZAWA et al.

Application No.: 09/864,309

Filed: May 25, 2001

For: EXPOSURE APPARATUS, COATING/DEVELOPING
SYSTEM, DEVICE MANUFACTURING SYSTEM,
DEVICE MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING FACTORY,
AND EXPOSURE APPARATUS MAINTENANCE
METHOD

)
: Examiner: R. A. Jarrett
)
: Group Art Unit: 2125
)
: Confirmation No.: 2803
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: July 29, 2005
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Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	14	MINUS	47	= 0	x \$25 \$50	\$0.00
INDEP. CLAIMS	1	MINUS	9	= 0	x \$100 \$200	\$0.00
Fee for Multiple Dependent claims \$180/\$360						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$_____ is enclosed including the additional claims fee.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$_____ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Steven E. Warner
Registration No. 33,326

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SEW/eab

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09/862.022239

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SEMICONDUCTOR MANUFACTURING FACTORY,) :
AND EXPOSURE APPARATUS MAINTENANCE) :
METHOD) :

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated April 29, 2005, please amend the above-identified application as follows: